

Notice of References Cited	Application/Control No. 09/892,417	Applicant(s)/Patent Under Reexamination HUPKES ET AL.	
	Examiner Fred Ferris	Art Unit 2128	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,532,428 B1	03-2003	Toprac, Anthony J.	702/97
	B	US-6,635,224 B1	10-2003	Gui et al.	422/62
	C	US-6,487,459 B1	11-2002	Martin et al.	700/44
	D	US-5,884,685 A	03-1999	Umezawa et al.	164/453
	E	US-5,918,191 A	06-1999	Patel, Tracy L.	702/84
	F	US-2003/0158680 A1	08-2003	Hupkes et al.	702/85
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Rugged Calibration for Process Control", P.J. Gemperline, Compans 95', October 1995
	V	"Using Qualitative Observations for Process Tuning and Control", C.J. Spanos et al, IEEE Transactions on Semiconductor Manufacturing, April 1998
	W	"Mudcats Metrology Suite", Technical Documentation, Edison ESI, 2002
	X	"The 811 Online IC defines new standards in process analysis" Metrohm Information, pp. 8-10, Issue 2/2001, Feb. 2001

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.